

JUL 25 2006

Docket No.: 4887P454X

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

STEVEN VERHAVERBEKE, ET AL.

Application No.: 09/891,849

Filed: June 25, 2001

For: Method and Apparatus for Wafer Cleaning

Art Group: 1746

Examiner: Markoff, Alexander

PETITION FOR EXTENSION OF TIME PURSUANT TO 37 C.F.R. § 1.136(a)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F. R. § 1.136(a), Applicants for the above-identified application respectfully Petition the Commissioner for a one (1) month extension of time, extending the period for response to July 24, 2006, from the Office Action dated March 22, 2006. The petition filing fee of \$120.00 and an Amendment and Response to Office Action are attached. (If a check is not attached, you are hereby authorized to charge deposit account no. 02-2666.)

If it should be determined that a longer extension of time is required to prevent this application from being abandoned, please charge any additional fees to Deposit Account No. 02-2666. A copy of the Fee Transmittal is enclosed for deposit account charging purposes.

Respectfully submitted,

Blakely, Sokoloff, Taylor & Zafman LLP

Date:

7/24/06Neal Berczny

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CERTIFICATE OF MAILING/TRANSMISSION

I hereby certify that this correspondence is being transmitted via facsimile on the date shown below to the United States Patent and Trademark Office.

Neal Berczny
Neal Berczny7/24/06
Date

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